



**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**In re Application of:**

Sandhu et al.

**Serial No.:** 10/637,102

**Filed:** August 8, 2003

**For:** LOW RESISTANCE CONTACT TO  
SILICON HAVING A TITANIUM SILICIDE  
INTERFACE AND AN AMORPHOUS  
TITANIUM CARBONITRIDE BARRIER  
LAYER

**Examiner:** Unknown

**Group Art Unit:** Unknown

**Attorney Docket No.:** 2269-3264.7US  
(92-0280.10/US)

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence along with any attachments referred to or identified as being attached or enclosed is being deposited with the United States Postal Service as First Class Mail on the date of deposit shown below with sufficient postage and in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

September 12, 2003  
Date

Signature

Deidra Pfeil

Name (Type/Print)

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In compliance with the duty to disclose information material to patentability pursuant to 37 C.F.R. § 1.56, it is respectfully requested that this Supplemental Information Disclosure Statement be entered and the document listed on attached Form PTO-1449 or PTO/SB/08 be considered by the Examiner and made of record. A copy of the listed document is enclosed pursuant to 37 C.F.R. § 1.98(a).

In accordance with 37 C.F.R. § 1.97(g) and (h), filing of this Supplemental Information Disclosure Statement is not to be construed as a representation that a search has been made or an admission that the information cited herein is, or is considered to be, material to patentability as

defined in 37 C.F.R. § 1.56(b). Further, no representation is made by Applicants herein that no other possible material information as defined in 37 C.F.R. § 1.56 (b) exists.

Other Documents

KATZ et al., "Properties of Titanium Nitride Thin Films Deposited by Rapid-Thermal-Low-Pressure-Metalorganic-Chemical-Vapor-Deposition Technique Using Tetrakis (Dimethylamido) Titanium Precursor", J. Appl. Phys. 70(7), October 1991, pps. 3666-3677.

Applicants offer to supply any explanation or discussion of the document which the Examiner feels is necessary or desirable and which is requested.

This Supplemental Information Disclosure Statement is filed within three (3) months of the filing date of the above-identified application.

Respectfully submitted,



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Date: September 12, 2003  
JRD/sls:djp

Enclosures: Form PTO-1449 or PTO/SB/08  
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PTO/SB/08B(10-01)

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**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Sheet

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of

1

**Complete if Known**

Application Number

10/637,102

Filing Date

August 8, 2003

First Named Inventor

Sandhu et al.

Group Art Unit

Unknown

Examiner Name

Unknown

Attorney Docket Number

3264 711S (92-0280 10/11S)

**OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS**

Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
		KATZ et al., "Properties of Titanium Nitride Thin Films Deposited by Rapid-Thermal-Low-Pressure-Metalorganic-Chemical-Vapor-Deposition Technique Using Tetrakis (Dimethylamido) Titanium Precursor", J. Appl. Phys. 70(7), October 1991, pps. 3666-3677.	

Examiner  
SignatureDate  
Considered

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<sup>1</sup> Unique citation designation number (optional). <sup>2</sup> Applicant is to place a check mark here if English language Translation is attached.

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